

Tae-Sun Yu

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/6802064/publications.pdf>

Version: 2024-02-01

16
papers

164
citations

1163117

8
h-index

1125743

13
g-index

16
all docs

16
docs citations

16
times ranked

71
citing authors

#	ARTICLE	IF	CITATIONS
1	Cleaning Plan Optimization for Dual-Armed Cluster Tools With General Chamber Cleaning Periods. IEEE Transactions on Automation Science and Engineering, 2023, 20, 1890-1906.	5.2	3
2	Feedback Control of Cluster Tools: Stability Against Random Time Disruptions. IEEE Transactions on Automation Science and Engineering, 2022, 19, 2008-2015.	5.2	2
3	Integrated Scheduling of a Dual-Armed Cluster Tool for Maximizing Steady Schedule Patterns. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2021, 51, 7282-7294.	9.3	5
4	Scheduling proportionate flow shops with preventive machine maintenance. International Journal of Production Economics, 2021, 231, 107874.	8.9	11
5	Reachability Tree-Based Optimization Algorithm for Cyclic Scheduling of Timed Petri Nets. IEEE Transactions on Automation Science and Engineering, 2021, 18, 1441-1452.	5.2	3
6	Scheduling of Flow Shop with Overlapping Waiting Time Constraints Using Genetic Algorithm. Journal of Korean Institute of Industrial Engineers, 2021, 47, 34-44.	0.1	3
7	Wafer Delay Analysis and Workload Balancing of Parallel Chambers for Dual-Armed Cluster Tools With Multiple Wafer Types. IEEE Transactions on Automation Science and Engineering, 2021, 18, 1516-1526.	5.2	8
8	Wafer delay analysis and control of dual-armed cluster tools with chamber cleaning operations. International Journal of Production Research, 2020, 58, 434-447.	7.5	8
9	Flow shops with reentry: Reversibility properties and makespan optimal schedules. European Journal of Operational Research, 2020, 282, 478-490.	5.7	11
10	Adaptive Scheduling of Cluster Tools With Wafer Delay Constraints and Process Time Variation. IEEE Transactions on Automation Science and Engineering, 2020, 17, 375-388.	5.2	8
11	Scheduling Dual-Armed Cluster Tools With Chamber Cleaning Operations. IEEE Transactions on Automation Science and Engineering, 2019, 16, 218-228.	5.2	24
12	Scheduling Dual-Armed Cluster Tools for Concurrent Processing of Multiple Wafer Types With Identical Job Flows. IEEE Transactions on Automation Science and Engineering, 2019, 16, 1058-1070.	5.2	14
13	A New Class of Sequences Without Interferences for Cluster Tools With Tight Wafer Delay Constraints. IEEE Transactions on Automation Science and Engineering, 2019, 16, 392-405.	5.2	9
14	Scheduling Single-Armed Cluster Tools With Chamber Cleaning Operations. IEEE Transactions on Automation Science and Engineering, 2018, 15, 705-716.	5.2	33
15	Minimization of Waiting Time Variation in a Generalized Two-Machine Flowshop With Waiting Time Constraints and Skipping Jobs. IEEE Transactions on Semiconductor Manufacturing, 2017, 30, 155-165.	1.7	17
16	Two-stage lot scheduling with waiting time constraints and due dates. , 2013, , .		5